



03500.015262

PATENT APPLICATION

QP-1762
JFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
: Examiner: M. Padgett
TAKESHI SHISHIDO ET AL.)
: Group Art Unit: 1762
Application No.: 09/822,191)
:
Filed: April 2, 2001)
:
For: EXHAUST PROCESSING METHOD,)
PLASMA PROCESSING METHOD :
AND PLASMA PROCESSING)
APPARATUS : August 25, 2004

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

a) Introductory Comments

In response to the Office Action date May 25, 2004, kindly amend the
subject application as follows.

I hereby certify that this correspondence is being deposited with the
United States Postal Service as first-class mail in an envelope addressed
to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-
1450 on

August 25, 2004
(Date of Deposit)

Jason M. Okun
(Name of Attorney for Applicants)


Signature

August 25, 2004
Date of Signature